

LIST OF REFERENCES CITED BY APPLICANT (Use several sheets if necessary)				ATTY. DOCKET NO. 9875-0008-999		APPLICATION NO. To be assigned	
				APPLICANT Hagelin et al.			
				FILING DATE July 25, 2003		GROUP 2872	

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
J.P.	5,867,297	2/1999	Kiang et al.				
J.P.	5,629,790	5/1997	Neukermans et al.				
J.P.	5,408,352	4/1995	Peng				
J.P.	4,317,611	3/1982	Peterson				
J.P.	5,361,158	11/1994	Tang				
J.P.	5,998,906	12/1999	Jerman et al.	310			

FOREIGN PATENT DOCUMENTS							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)	
J.P.	Daneman et al., "Integrated Laser-to-Fiber Coupling Module Using a Micromachined Alignment Mirror", <i>Conference on Lasers and Electro-Optics</i> , 1995, Technical Digest Series, Vol. 15, pp.245-250, Baltimore, MD, May 1995.
J.P.	Daneman et al., "Linear Microvibromotor for Positioning Optical Components", <i>J of Microelectromechanical Systems</i> , 5(3):159-165 (1996).
J.P.	Daneman et al., "Linear Vibromotor-Actuated Micromachined Microreflector for Integrated Optical Systems", <i>Solid-State Sensor and Actuator Workshop</i> , Hilton Head, SC, June 2-6 1996.
J.P.	Deng et al., "The Development of Polysilicon Micromotors for Optical Scanning Applications", <i>Solid-State Sensor and Actuator Workshop</i> , pp. 234-238, Hilton Head, SC, June 13-16, 1994.
J.P.	Kiang et al., "Electrostatic Combedrive-Actuated Micromirrors for Laser-Beam Scanning and Positioning", <i>J of Microelectromechanical Systems</i> , 7(1):27-37, March 1998.
J.P.	Kiang et al., "High-Precision Si-Micromachined Micromirrors with On-Chip Actuation for External-Cavity Semiconductor Lasers", <i>Conference on Lasers and Electro-Optics</i> , Technical Digest Series, Vol. 15, pp. 248-249, Baltimore, MD, May 1995.
J.P.	Kiang et al., "Micromachined Polysilicon Microscanners for Barcode Readers", <i>IEEE Photonics Technology Letters</i> , 8(12):1707-1709, December 1996.
J.P.	Kiang et al., "Silicon-Micromachined Micromirrors with Integrated High-Precision Actuators for External-Cavity Semiconductor Lasers", <i>IEEE Photonics Technology Letters</i> , 8(1):95-97 (1996).
J.P.	Pister et al., "Microfabricated Hinges", <i>Sensors and Actuators</i> , 33(3):249-256 (1992).
J.P.	Solgaard, O., "High-Resolution Silicon Surface Micromachined Displays", (invited talk), <i>Technical Digest of the IEEE/LEOS IEEJ/SAMS 1997 International Conference on Optal MEMS and their Applications (MOEMS97)</i> , pp. 9-14, Nara, Japan, November 18-21, 1997.
J.P.	Solgaard et al., "Optoelectronic Packaging Using Silicon Surface-Micromachined Alignment Mirrors", <i>IEEE Photonics Technology Letters</i> , 7(1):41-43 (1995).
J.P.	Solgaard et al., "Precision and Performance of Polysilicon Micromirrors for Hybrid Integrated Optics", <i>SPIE, Symposium on Lasers and Applications</i> , San Jose, CA, February 1995.
J.P.	Tien et al., "Surface-Micromachined Mirrors for Laser-Beam Positioning", <i>Sensors and Actuators</i> , A 52:76-80 (1996).
J.P.	Tsufura et al., "Barcode Scanning On-Going Evolution & Development", <i>Lasers & Optonics</i> , July 1995.

J.P.		Yasseen et al., "Diffraction Grating Scanners Using Polysilicon Micromotors", <i>Proceedings IEEE Micro Electro Mechanical Systems</i> , pp. 175-180, Amsterdam, The Netherlands, January 1995.
J.P.		Lin et al. "Free-Space Micromachined Optical Switches with Submillisecond Switching Time for Large-Scale Optical Crossconnects", <i>IEEE Photonics Technology Letters</i> , Vol. 10, No. 4, April 1998, pp 525-527.
EXAMINER		DATE CONSIDERED
James Phan		5/17/04
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>		